

FIG. 1

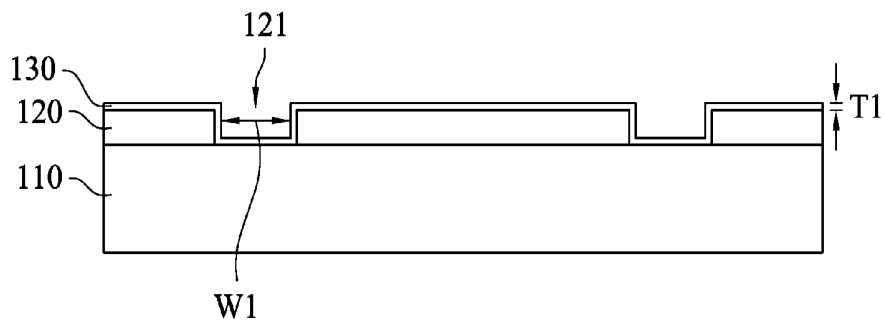


FIG. 2

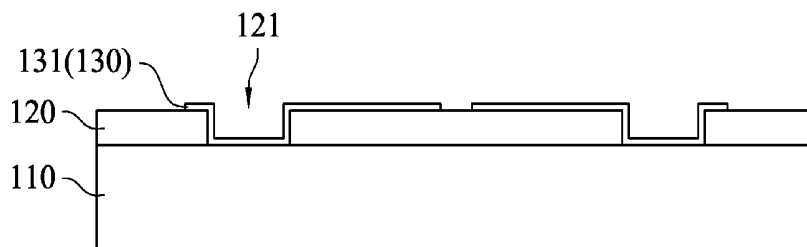


FIG. 3

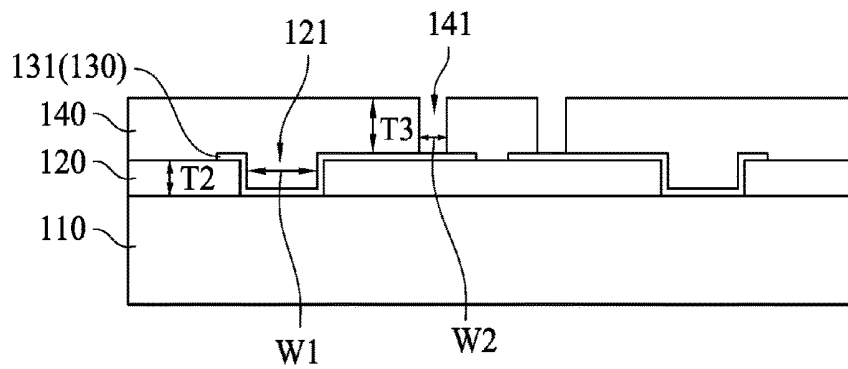


FIG. 4

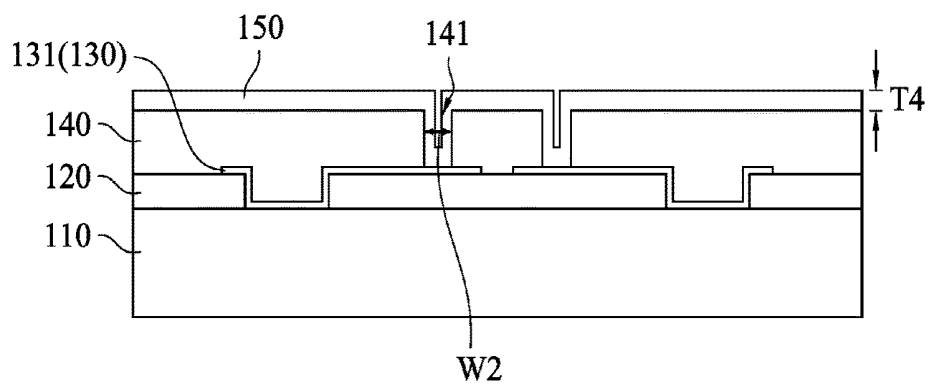


FIG. 5

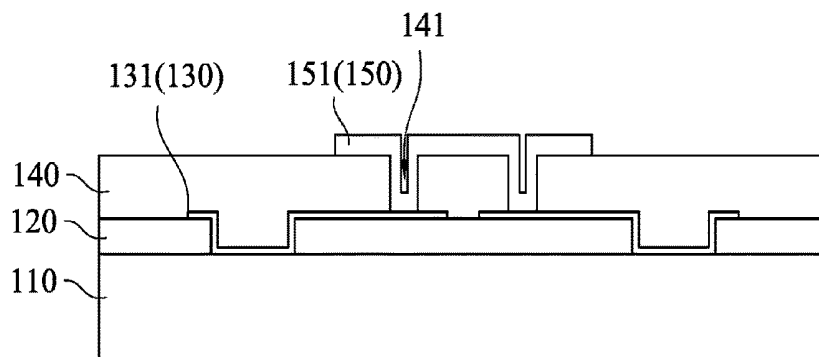


FIG. 6

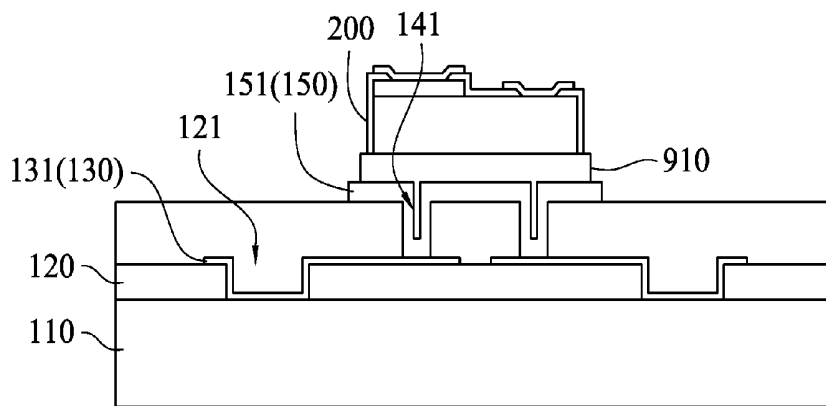


FIG. 7

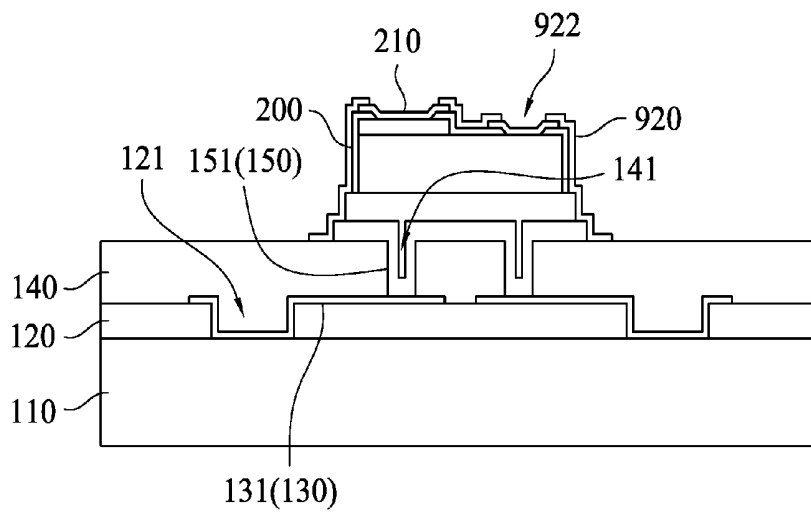


FIG. 8

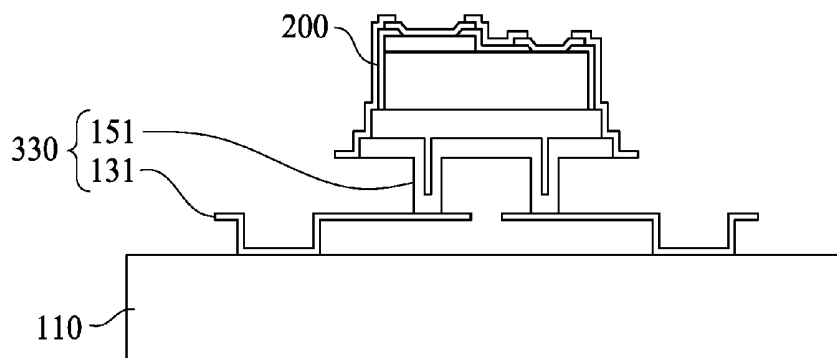


FIG. 9

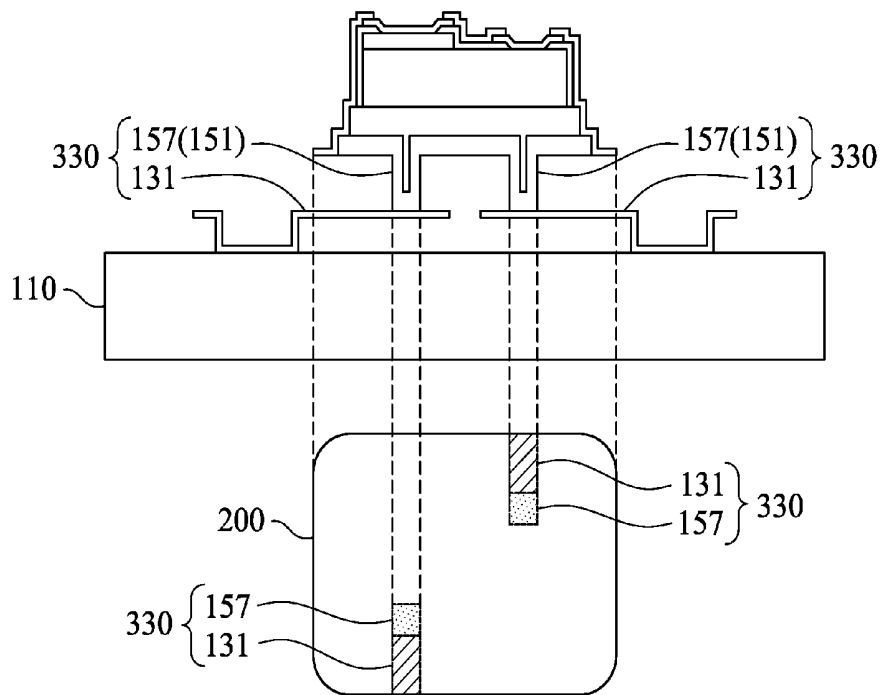


FIG. 10A

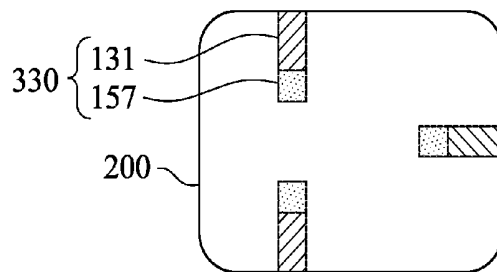


FIG. 10B

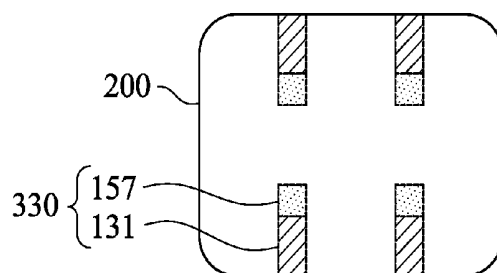


FIG. 10C

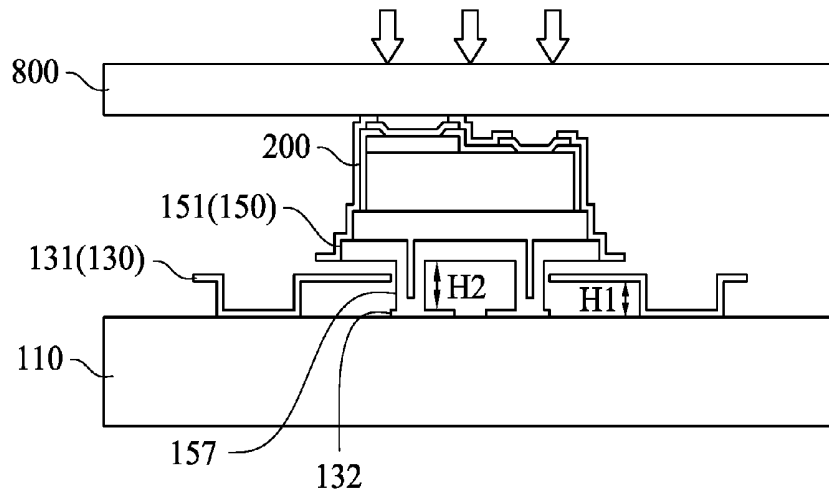


FIG. 11

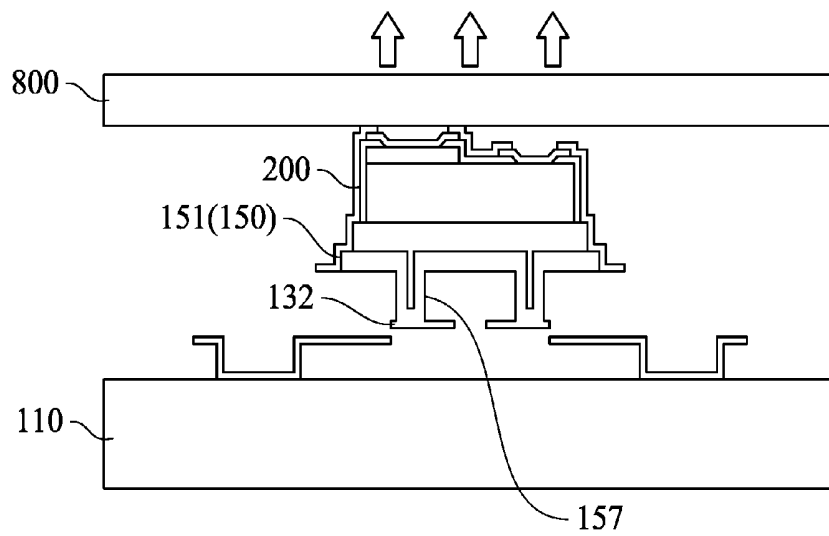


FIG. 12

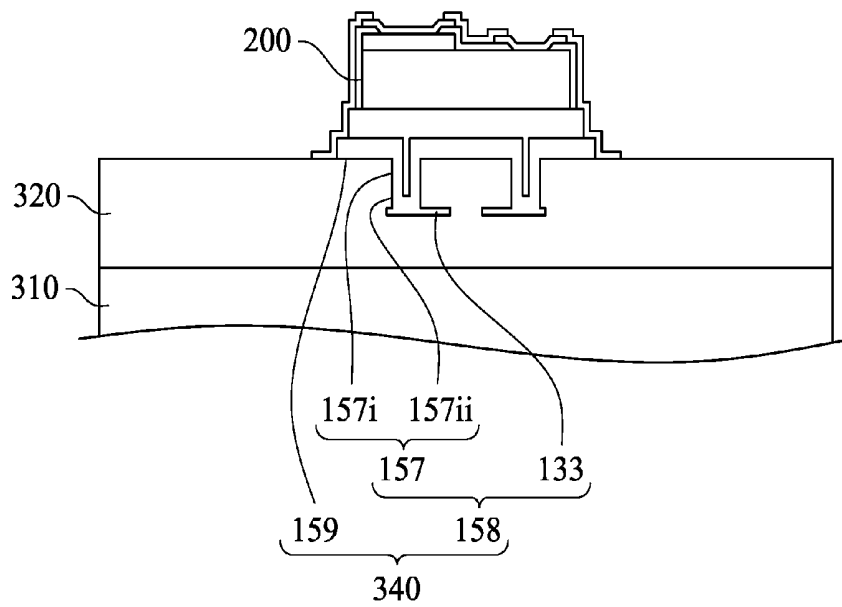


FIG. 13

1 DISPLAY PANEL

BACKGROUND

Technical Field

The present invention relates to a display panel and a method for forming a micro component support.

Related Art

A problem that occurs during packaging is usually one of the bottlenecks of mass production of micro components such as semiconductor induction apparatuses, semiconductor laser arrays, micro-electro-mechanical systems (MEMS), and light emitting diode display systems.

In a conventional method for transferring a micro component, a micro component is transferred from a carrier substrate to a receiving substrate by means of wafer bonding. One implementation method of the wafer bonding is direct bonding in which a micro component array is directly bonded from a carrier substrate to a receiving substrate, and then the carrier substrate is removed. Another implementation method of the wafer bonding is indirect bonding in which bonding/splitting needs to be performed twice. During indirect bonding, first, a transfer apparatus extracts a micro component array from a carrier substrate; then, the transfer apparatus bonds the micro component array to a receiving substrate; and finally, the transfer apparatus is removed.

SUMMARY

A technical aspect of the present invention provides a method for forming a micro component support, to improve process yield and process efficiency.

According to an implementation of the present invention, the method for forming a micro component support includes the following steps. First, a first sacrificial layer is formed on a carrier substrate, wherein the first sacrificial layer includes a plurality of first openings, and the first openings expose the carrier substrate. Then, a first support layer is formed on the first sacrificial layer and in the first openings. Next, a second sacrificial layer is formed on the first sacrificial layer and the first support layer, wherein the second sacrificial layer includes a plurality of second openings, and the second openings expose the first support layer. Then, a second support layer is formed on the second sacrificial layer and in the second openings. Finally, the first sacrificial layer and the second sacrificial layer are removed after forming a micro component on the second support layer.

In one or more implementations of the present invention, the method further includes the following steps. First, a transfer apparatus is disposed on the micro component. Then, the transfer apparatus is caused to apply a downforce via the micro component to the second support layer, and to break the first support layer where the first support layer connects to the second support layer.

In one or more implementations of the present invention, the method further includes the following steps. The transfer apparatus drives the micro component, the second support layer, and the break-off part to move downwardly, so that the break-off part is in contact with the carrier substrate, and the second support layer is not in contact with the other part of the first support layer.

According to another implementation of the present invention, a display panel is provided, including: a display

2

substrate, a fixing layer, a support, and a micro component. The fixing layer is disposed on the display substrate. The support includes a platform portion and a plurality of extending portions, where the platform portion is disposed on the fixing layer, and the extending portions extend from the platform portion to the fixing layer. The micro component is disposed on the platform portion.

In one or more implementations of the present invention, each of the extending portions further includes a vertically extending portion and a horizontally extending portion. The vertically extending portion includes a first end and a second end, where the first end is connected to the platform portion, and the horizontally extending portion is connected to the second end.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 to FIG. 9 are schematic cross-sectional views of process steps of a micro component support according to an implementation of the present invention;

FIG. 10A is a schematic cross-sectional view and a schematic top view of a micro component support according to an implementation of the present invention;

FIG. 10B and FIG. 10C are schematic top views of a micro component support according to different implementations of the present invention; and

FIG. 11 to FIG. 13 are schematic cross-sectional views of process steps of transferring a micro component according to an implementation of the present invention.

DETAILED DESCRIPTION

The following describes a plurality of implementations of the present invention by using drawings. For clarity of illustration, many practical details are described below. However, it should be understood that these practical details should not be construed as a limitation to the present invention. That is, in some implementations of the present invention, these practical details are not necessary. In addition, for simplicity of the drawings, some conventional structures and components are shown in the drawings in a simplified schematic manner.

FIG. 1 to FIG. 9 are schematic cross-sectional views of process steps of a micro component support according to an implementation of the present invention. First, as shown in FIG. 1, a first sacrificial layer 120 is formed on a carrier substrate 110. The first sacrificial layer 120 includes a plurality of first openings 121, and the first openings 121 expose the carrier substrate 110. In other words, the first sacrificial layer 120 does not cover a part of the carrier substrate 110.

For example, the material of the carrier substrate 110 may be glass, silicon, sapphire, or another proper material. The first sacrificial layer 120 may have a single layer or multiple layers, and the material of the first sacrificial layer 120 may be an inorganic material (such as metal), an organic material (such as photoresist), or another proper material. The first sacrificial layer 120 may be formed by using a deposition process, a coating process, or another proper process. The first openings 121 may be formed by using a lithography and etching process, a photolithography process, or another proper process.

As shown in FIG. 2, a first support layer 130 is formed on the first sacrificial layer 120 and in the first openings 121. For example, the thickness T1 of the first support layer 130 is substantially less than the width W1 of the first opening 121, and the first support layer 130 is conformally formed on

the first sacrificial layer **120** and in the first openings **121**. Further, because the thickness **T1** of the first support layer **130** is substantially less than the width **W1** of the first opening **121**, the first support layer **130** may be conformally formed in the first openings **121**. In this way, it is convenient to use the part that is of the first support layer **130** and that is conformally formed in the first openings **121** as a bracket portion of a support that is formed by using a subsequent process.

In an embodiment, a part of the first support layer **130** is formed on and in contact with the carrier substrate **110**, and the other part of the first support layer **130** is formed on and in contact with the first sacrificial layer **120**. The first support layer **130** may have a single layer or multiple layers, and the material of the first support layer **130** may be silicon oxide, silicon nitride, amorphous silicon, or another proper material. The first support layer **130** may be formed by using a deposition process or another proper process.

As shown in FIG. 3, the first support layer **130** is patterned, so that the first support layer **130** includes a plurality of first support portions **131**. The first support portions **131** are mutually separated (For example, there is a gap not shown that separates two adjacent first support portions **131**). A part of each first support portion **131** is respectively disposed in the first openings **121** and on the carrier substrate **110**, and the other part of the first support portion **131** is disposed on the first sacrificial layer **120**.

As shown in FIG. 4, a second sacrificial layer **140** is formed on the first sacrificial layer **120** and the first support portions **131** (the first support layer **130**). The second sacrificial layer **140** includes a plurality of second openings **141**. The second openings **141** expose a part of each first support portion **131** (the first support layer **130**). In other words, the second sacrificial layer **140** does not cover the other part of each first support portion **131**. For example, the material of the second sacrificial layer **140** may be an inorganic material (such as metal), an organic material (such as photoresist), or another proper material. The second sacrificial layer **140** may be formed by using a deposition process, a photolithography process, or another proper process. The material of the second sacrificial layer **140** may be substantially the same as or different from the material of the first sacrificial layer **120**.

An orthographic projection (or referred to as a vertical projection) of each first opening **121** on the carrier substrate **110** and an orthographic projection of each second opening **141** on the carrier substrate **110** are not overlapped.

The width **W2** of the second opening **141** is substantially less than the width **W1** of the first opening **121**, and the thickness **T3** of the second sacrificial layer **140** is substantially greater than the thickness **T2** of the first sacrificial layer **120**. The width **W2** of the second opening **141** is substantially less than the width **W1** of the first opening **121**, so that it is convenient to achieve process integrity.

As shown in FIG. 5, a second support layer **150** is formed on the second sacrificial layer **140** and in the second openings **141**. For example, the thickness **T4** of the second support layer **150** is substantially less than the width **W2** of the second opening **141**, and the second support layer **150** is conformally formed on the second sacrificial layer **140** and in the second openings **141**. Further, because the thickness **T4** of the second support layer **150** is substantially less than the width **W2** of the second opening **141**, the second support layer **150** may be conformally formed in the second openings **141**. In this way, it is convenient to use the part that is of the second support layer **150** and that is conformally

formed in the second openings **141** as a bracket portion of the support that is formed by using a subsequent process.

In an embodiment, a part of the second support layer **150** is formed on and in contact with the first support portions **131** (the first support layer **130**), and the other part of the second support layer **150** is formed on and in contact with the second sacrificial layer **140**. The second support layer **150** may include a single layer or multiple layers, and the material of the second support layer **150** may be silicon oxide, silicon nitride, amorphous silicon, metal, or another proper material. The second support layer **150** may be formed by using a deposition process or another proper process.

For example, the thickness **T4** of the second support layer **150** is substantially greater than the thickness **T1** of the first support layer **130**. The thickness **T4** of the second support layer **150** is substantially greater than the thickness **T1** of the first support layer **130**, so that an upper part of the support that is formed by using a subsequent process has relatively great rigidity, and a lower part of the support has relatively small rigidity.

In this implementation, the width **W2** of the second opening **141** is only multiple times, for example, two to three times the thickness of the second support layer **150**. Therefore, the part of the second support layer **150** that is in the second openings **141** is in a form of a cylinder. In this embodiment, a vertical side wall is used as an example of a side wall of each first opening **121** and/or a side wall of each second opening **141**, but this is not limited thereto. In another embodiment, the side wall of the first opening **121** and/or the side wall of the second opening **141** may be an inclined side, that is, may have a slope.

As shown in FIG. 6, the second support layer **150** is patterned, so that the second support layer **150** includes a plurality of second support portions **151**. The second support portions **151** are mutually separated. A part of each second support portion **151** is respectively disposed in the second openings **141** and on the first support portions **131**, and the other part of the second support portion **151** is disposed on the second sacrificial layer **140**.

Further, each second support portion **151** is respectively connected to a plurality of different first support portions **131**. In this implementation, each second support portion **151** is connected to two first support portions **131**. For example, each second support portion **151** is connected to two adjacent first support portions **131**. In other words, each second support portion **151** respectively partially overlaps the two first support portions **131**, and each second support portion **151** also partially overlaps a gap (such as a place that is not shown and in which the first support portions **131** are mutually separated) between the two first support portions **131**.

As shown in FIG. 7, at least one micro component **200** is formed on the second support portions **151** (the second support layer **150**). Specifically, the micro component **200** is a micro light emitting diode or another proper micro component (such as a photoreceptor, a transistor, or another proper component). In this embodiment, a micro light emitting diode is used as an example of the at least one micro component **200**, but this is not limited thereto. Two horizontally arranged electrodes **210** (refer to FIG. 8) that are respectively connected to an electron hole layer (such as a P-type semiconductor or another proper material) and an electron layer (such as an N-type semiconductor or another proper material) are used as an example of the micro light emitting diode, but this is not limited thereto. In another embodiment, the micro light emitting diode includes two

vertically arranged electrodes that are respectively connected to an electron hole layer and an electron layer. The photoreceptor may be a visible light photoreceptor, a UV photoreceptor, an IR photoreceptor, or another proper photoreceptor. The transistor may be a bottom-gate transistor, a top-gate transistor, a three-dimensional pass transistor, or another proper transistor. The micro component 200 may be transferred from another substrate (such as a generation substrate) by using a transfer apparatus and fixed on the second support portions 151, but this is not limited thereto. In another embodiment, the micro component 200 may be further directly formed on the second support portions 151.

A part of each second support portion 151 disposed on the second sacrificial layer 140 is in a form of a platform, so that the micro component 200 can be well fixed on the second support portions 151.

In some embodiments, when the micro component 200 is transferred from another substrate (such as a generation substrate) by using a transfer apparatus and fixed on the second support portions 151, before the micro component 200 is fixed, a patterned adhesive layer 910 may be formed on the second support portions 151 (the second support layer 150). Then, the micro component 200 is formed (for example, disposed) on the adhesive layer 910, so that the micro component 200 is fixed on the second support portions 151 (the second support layer 150).

As shown in FIG. 8, an insulating film 920 is deposited and patterned, so that the insulating film 920 covers the micro component 200. When the insulating film 920 is patterned, a contact hole 922 is formed, so that the electrodes 210 of the micro component 200 are exposed. The insulating film 920 may have a single layer or multiple layers, and the material of the insulating film 920 may be silicon oxide, silicon nitride, amorphous silicon, or another proper material.

As shown in FIG. 9, the first sacrificial layer 120 and the second sacrificial layer 140 are removed, so that the remaining first support portions 131 and the second support portions 151 form a micro component support 330. The micro component support 330 supports and fixes the micro component 200 onto the carrier substrate 110. The first sacrificial layer 120 and the second sacrificial layer 140 may be removed by using a chemical etching process or another proper process.

In this implementation, two first support portions 131 and one second support portion 151 form one micro component support 330, but this is not limited thereto. In another implementation, more than two first support portions 131 and one second support portion 151 may form one micro component support 330.

FIG. 10A is a schematic cross-sectional view and a schematic top view of a micro component support 330 according to an implementation of the present invention. As shown in FIG. 10A, a second support portion 151 includes two vertically extending portions 157, and the two vertically extending portions 157 are respectively connected to two first support portions 131. It can be learned from the schematic top view that the two vertically extending portions 157 are respectively and roughly disposed at two opposite angles or on a diagonal path of the micro component 200. The two second support portions 151 are also respectively and correspondingly disposed at two opposite angles or on a diagonal path of the micro component 200. It should be noted herein that only a contour of the micro component 200 is shown in the schematic top view, and a detailed structure is not shown.

FIG. 10B and FIG. 10C are schematic top views of a micro component support 330 according to different implementations of the present invention. As shown in FIG. 10B and FIG. 10C, the micro component support 330 does not necessarily include only two vertically extending portions 157 and two first support portions 131. In FIG. 10B, the micro component support 330 includes three vertically extending portions 157 and three first support portions 131. The three vertically extending portions 157 are respectively connected to the three first support portions 131. The three vertically extending portions 157 are respectively disposed on locations that are adjacent to two opposite sides of the micro component 200 and a location that is adjacent to an adjacent side that connects the two opposite sides, and the adjacent side is an adjacent side that is of two adjacent sides connecting the two opposite sides and that is remoter relative to the vertically extending portions 157 that are disposed adjacent to the two opposite sides. The three vertically extending portions 157 are respectively and correspondingly disposed on locations that are adjacent to the two opposite sides of the micro component 200 and a location that is adjacent to an adjacent side that connects the two opposite sides.

In FIG. 10C, the micro component support 330 includes four vertically extending portions 157 and four first support portions 131. The four vertically extending portions 157 are respectively connected to the four first support portions 131. The four vertically extending portions 157 are respectively and roughly disposed at four corners of the micro component, and the four second support portion 151 are also respectively and correspondingly disposed at the four corners of the micro component 200, but this is not limited thereto. In another embodiment, two of the four vertically extending portions 157 are disposed adjacent to one of the two opposite sides of the micro component 200, and the other two vertically extending portions 157 are disposed adjacent to the other of the two opposite sides of the micro component 200.

In the foregoing architecture, the micro component support 330 includes multiple branches that are connected to the micro component 200 and the carrier substrate 110 (refer to FIG. 10A), so that the micro component 200 is prevented from falling off from the carrier substrate 110.

Further, due to the setting of the locations of the vertically extending portions 157 and the first support portions 131, weight of the micro component 200 may be evenly distributed by using the micro component support 330, so that the micro component 200 can be well fixed on the carrier substrate 110.

FIG. 11 to FIG. 13 are schematic cross-sectional views of process steps of transferring a micro component 200 according to an implementation of the present invention. First, as shown in FIG. 11, a transfer apparatus 800 is disposed on the micro component 200. Then, the transfer apparatus 800 is caused to apply a downward pressure (such as a pressure or a thrust formed by the transfer apparatus 800 moving toward an inner surface of a carrier substrate 110) via the micro component 200 to a second support portions 151 (a second support layer 150), and a break-off part 132 that is of a first support portion 131 (a first support layer 130) and that is connected to the second support portion 151 (the second support layer 150) is caused to break off from the other part of the first support portion 131 (the first support layer 130). For example, the break-off part 132 is adjacent to a gap (not shown) between two first support portions 131 or adjacent to a neighboring place of the gap, but this is not limited thereto.

In another embodiment, the break-off part **132** may be further another location that is prone to break-off.

It should be noted that the transfer apparatus **800** herein needs to apply only a downward pressure (or referred to as a downforce) to the micro component **200**, and does not need to apply a horizontal force for a rightward or leftward displacement, so that the micro component **200** is prevented from being displaced, tilted, or falling off.

After the break-off part **132** of the first support portion **131** breaks off from the other part of the first support portion **131**, the transfer apparatus **800** drives the micro component **200**, the second support portion **151** (the second support layer **150**), and the break-off part **132** (a part of the first support portion **131**) to move downwardly, so that the break-off part **132** is in contact with the carrier substrate **110**.

As shown in FIG. 4 and FIG. 11, because the orthographic projection of the first opening **121** on the carrier substrate **110** and the orthographic projection of the second opening **141** on carrier substrate **110** are not overlapped, an orthographic projection on the carrier substrate **110** of the first support portion **131** formed in the first opening **121** and an orthographic projection on the carrier substrate **110** of the vertically extending portion **157** of the second support portion **151** formed in the second opening **141** are not overlapped. In this way, the break-off part **132** that is connected to the vertically extending portion **157** is suspended, and there is a gap between the break-off part **132** and the carrier substrate **110**. When the transfer apparatus **800** applies a downward pressure via the micro component **200** to the second support portion **151**, because the break-off part **132** is suspended, the break-off part **132** breaks off from the other part of the first support portion **131**, and the micro component **200**, the second support portion **151** and the break-off part **132** (a part of the first support portion **131**) move downwardly. In this way, the break-off part **132** is in contact with the carrier substrate **110**.

Further, because the thickness **T3** of the second sacrificial layer **140** is substantially greater than the thickness **T2** of the first sacrificial layer **120**, the height **H2** of the vertically extending portion **157** of the second support portion **151** is caused to be substantially greater than the height **H1** of the first support portion **131**. In this case, when the break-off part **132** is in contact with the carrier substrate **110**, the second support portion **151** (the second support layer **150**) is in contact with only the break-off part **132**, and is not in contact with the other part of the first support portion **131** (the first support layer **130**).

As shown in FIG. 12, the transfer apparatus **800** extracts the micro component **200**, and extracts, at the same time, the second support portion **151** and the break-off part **132** that are connected to the micro component **200**.

As shown in FIG. 13, the transfer apparatus **800** (refer to FIG. 12) places the micro component **200** on a fixing layer **320** of a display substrate **310** (or referred to as a receiving substrate). In this case, an adhesive force of the fixing layer **320** is substantially greater than an attraction force (or referred to as an adhesive force) of the transfer apparatus **800** on the micro component **200**. Therefore, after the micro component **200** is placed on the fixing layer **320**, the micro component **200** adheres to the fixing layer **320** and falls off from the transfer apparatus **800**.

As shown in FIG. 11, for the second support portion **151** and the break-off part **132** that are connected to the micro component **200**, only the break-off part **132** is in contact with the carrier substrate **110**, and a contact area between the break-off part **132** and the carrier substrate **110** is not large. Therefore, it is not necessary to worry that after being in

contact for an excessively long period, the break-off part **132** and the carrier substrate **110** are electrostatically attracted to each other and then the micro component **200** cannot be extracted from the carrier substrate **110**. Therefore, on the foregoing premise, the transfer apparatus **800** does not need to apply a relatively great downforce to reduce a time of contact between the break-off part **132** and the carrier substrate **110**, and the micro component **200** can be prevented from being damaged because of an excessively great downforce.

Further, in the foregoing architecture, the contact area between the break-off part **132** and the carrier substrate **110** is not large, so that a tool that has a relatively small line width does not need to be changed to specially to reduce the contact area between the break-off part **132** and the carrier substrate **110**. Therefore, for the entire process, a requirement for constructing multiple components is avoided, so that process yield and process efficiency can be further improved.

As shown in FIG. 13, another implementation of the present invention provides a display panel **300**. The display panel **300** includes: a display substrate **310**, a fixing layer **320**, at least one support **340**, and at least one micro component **200**. The fixing layer **320** is disposed on the display substrate **310**. The support **340** includes a platform portion **159** and a plurality of extending portions **158**. The platform portion **159** is disposed on the fixing layer **320**, and the extending portions **158** extend from the platform portion **159** to the fixing layer **320**. The micro component **200** is disposed on the platform portion **159**.

The material of the fixing layer **320** may be an organic material (such as photoresist). It should be noted that the foregoing specific implementation of the fixing layer **320** is merely an example, and is not intended to limit the present invention. A person of ordinary skill in the technical field to which the present invention belongs should select a specific implementation of the fixing layer **320** according to an actual requirement.

Each extending portion **158** further includes a vertically extending portion **157** and a horizontally extending portion **133**. The vertically extending portion **157** includes a first end **157i** and a second end **157ii**. The first end **157i** is connected to the platform portion **159** and the horizontally extending portion **133** is connected to the second end **157ii**.

In some embodiments, the width of the vertically extending portion **157** is substantially greater than the thickness of the horizontally extending portion **133**, and the length of the vertically extending portion **157** is substantially greater than the thickness of the horizontally extending portion **133**. It should be noted that the foregoing specific implementations of the vertically extending portion **157** and the horizontally extending portion **133** are merely examples, and are not intended to limit the present invention. A person of ordinary skill in the technical field to which the present invention belongs should select specific implementations of the vertically extending portion **157** and the horizontally extending portion **133** according to an actual requirement.

In some embodiments, the thickness of the platform portion **159** is substantially greater than the thickness of the horizontally extending portion **133**, and the thickness of the platform portion **159** is substantially less than the width of the vertically extending portion **157**. It should be noted that the foregoing specific implementations of the platform portion **159**, the horizontally extending portion **133**, and the vertically extending portion **157** are merely examples, and are not intended to limit the present invention. A person of ordinary skill in the technical field to which the present

invention belongs should select specific implementations of the platform portion **159**, the horizontally extending portion **133**, and the vertically extending portion **157** according to an actual requirement.

In some embodiments, the length of vertically extending portion **157** is substantially greater than the width of the vertically extending portion **157**. It should be noted that the foregoing specific implementation of the vertically extending portion **157** is merely an example, and is not intended to limit the present invention. A person of ordinary skill in the technical field to which the present invention belongs should select a specific implementation of the vertically extending portion **157** according to an actual requirement.

A type of the micro component **200** in this embodiment may be the same as that described above in the foregoing embodiment, and details are not described herein again.

In the foregoing implementation of the present invention, because the micro component support includes multiple branches that are connected to the micro component and the carrier substrate, the micro component is prevented from falling off from the carrier substrate.

Further, for a second support portion and a break-off part that are connected to the micro component, only the break-off part is in contact with the carrier substrate, and a contact area between the break-off part and the carrier substrate is not large. Therefore, it is not necessary to worry that after being in contact for an excessively long period, the break-off part and the carrier substrate are electrostatically attracted to each other and then the micro component cannot be extracted from the carrier substrate. Therefore, on the foregoing premise, a transfer apparatus does not need to apply a relatively great downforce to reduce a time of contact between the break-off part and the carrier substrate, so that the micro component can be prevented from being damaged because of an excessively great downforce.

Further, in the foregoing architecture, the contact area between the break-off part and the carrier substrate is not large, so that a tool that has a relatively small line width does not need to be changed to specially to reduce the contact area between the break-off part and the carrier substrate. Therefore, for the entire process, a requirement for constructing multiple components is avoided, so that process yield and process efficiency can be further improved.

Although the present invention has been disclosed by using the implementations, the implementations are not intended to limit the present invention, and a person skilled

in the art may make various modifications and improvements without departing from the spirit and scope of the present invention. Therefore, the protection scope of the present invention should be subject to the scope defined by the claims.

What is claimed is:

1. A display panel, comprising:

a display substrate;

a fixing layer, disposed on the display substrate;

a support, comprising a platform portion and a plurality of extending portions, wherein the platform portion is disposed on the fixing layer, and the extending portions extend from the platform portion to the fixing layer; and

a micro component, disposed on the platform portion; wherein each of the extending portions further comprises:

a vertically extending portion, comprising a first end and a second end, wherein the first end is connected to the platform portion; and

a horizontally extending portion, connected to the second end.

2. The display panel according to claim 1, wherein a width of the vertically extending portion is greater than a thickness of the horizontally extending portion.

3. The display panel according to claim 1, wherein a length of the vertically extending portion is greater than a thickness of the horizontally extending portion.

4. The display panel according to claim 1, wherein the platform portion is thicker than the horizontally extending portion.

5. The display panel according to claim 1, wherein a thickness of the platform portion is less than a width of the vertically extending portion.

6. The display panel according to claim 1, wherein a length of the vertically extending portion is greater than a width of the vertically extending portion.

7. The display panel according to claim 1, wherein the horizontally extending portion is formed by a first support layer, and the platform portion and the vertically extending portion are formed by a second support layer.

8. The display panel according to claim 1, wherein the platform portion is disposed on a surface of the fixing layer, and the extending portions are disposed in the fixing layer.

9. The display panel according to claim 1, wherein the micro component is a micro light emitting diode.

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摘要(译)

提供一种显示面板和用于形成微元件支撑件的方法。形成微元件支撑件的方法包括以下步骤。首先，在载体衬底上形成第一牺牲层，其中第一牺牲层包括多个第一开口，并且第一开口暴露载体衬底。然后，在第一牺牲层上和第一开口中形成第一支撑层。接着，在第一牺牲层和第一支撑层上形成第二牺牲层，其中第二牺牲层包括多个第二开口，第二开口暴露第一支撑层。然后，在第二牺牲层上和第二开口中形成第二支撑层。接下来，在第二支撑层上形成至少一个微组件。最后，去除第一牺牲层和第二牺牲层。

